

ABSTRACT

METHOD AND SYSTEM FOR CONTROLLING HOISTING MECHANISM OF OVERHEAD HOIST VEHICLE

The present disclosure provides a method and a system for controlling hoisting mechanism of an overhead hoist vehicle, applicable to the field of manufacturing equipment for semiconductor wafer. The method includes: activating the hoisting mechanism to drive the clamping mechanism to move in response to the overhead hoist vehicle travelling to a preset position on a track; and acquiring a moving velocity of the clamping mechanism, and performing a respective subsection control of a plurality of subsection controls according to the moving velocity. By acquiring the moving velocity of the clamping mechanism in real time, and performing the steady and fast plurality of subsection controls on the movement of the clamping mechanism based on the real-time moving velocity, the movement of the clamping mechanism can be steady, and the travel cycle of the movement can be significantly optimized, thereby greatly improving efficiency of wafer handling in automation applications in a semiconductor plant, and being conducive to improvement of production efficiency of wafers.

Figure 3